



DT20 Rec'd PCT/PTO 2 MAY 2003

PATENT #14
Docket No.: 29273/516 #15

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT : Shigeo Moriyama, et al.
SERIAL NO. : 09/462,912
FILING DATE : January 18, 2000
FOR : POLISHING APPARATUS AND METHOD FOR PRODUCING SEMICONDUCTORS USING THE APPARATUS
GROUP ART UNIT : 3723
EXAMINER : Unknown

COMMISSIONER FOR PATENTS
P.O. Box 1450
Alexandria, VA 22313-1450

RECEIVED
JUN 05 2003
TECHNOLOGY CENTER R3700

REQUEST FOR CORRECTED FILING RECEIPT

SIR:

Attached is a copy of the official filing receipt received from the PTO in the above application for which issuance of a corrected filing receipt is respectfully requested.

The errors are listed below.

ERROR IN

Title:

Polishing apparatus and a semiconductor manufacturing method using the same

CORRECT DATA

Title should read:

**POLISHING APPARATUS AND
METHOD FOR PRODUCING
SEMICONDUCTORS USING THE
APPARATUS**

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Docket No.: 29273/516

The Examiner is invited to call the undersigned at (202) 220-4200 to discuss any information concerning this application.

The Office is hereby authorized to charge any additional fees under 37 C.F.R. § 1.16 or § 1.17 or credit any overpayment to Deposit Account No. 11-0600.

Respectfully submitted,

KENYON & KENYON

Date: 5/12/03



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**UNITED STATES
PATENT AND
TRADEMARK OFFICE**

 Commissioner for Patents
 Washington, DC 20231
 www.uspto.gov

APPLICATION NUMBER	FILING DATE	GRP ART UNIT	FIL FEE REC'D	ATTY.DOCKET.NO	DRAWINGS	TOT CLAIMS	IND CLAIMS
09/462,912	01/18/2000	3723	840	29273/516	8	11	3

26646
 KENYON & KENYON
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 NEW YORK, NY 10004

CONFIRMATION NO. 5646
FILING RECEIPT

 OC000000009817265

Date Mailed: 04/14/2003

Receipt is acknowledged of this regular Patent Application. It will be considered in its order and you will be notified as to the results of the examination. Be sure to provide the U.S. APPLICATION NUMBER, FILING DATE, NAME OF APPLICANT, and TITLE OF INVENTION when inquiring about this application. Fees transmitted by check or draft are subject to collection. Please verify the accuracy of the data presented on this receipt. If an error is noted on this Filing Receipt, please write to the Office of Initial Patent Examination's Filing Recipt Corrections, facsimile number 703-746-9195. Please provide a copy of this Filing Receipt with the changes noted thereon. If you received a "Notice to File Missing Parts" for this application, please submit any corrections to this Filing Receipt with your reply to the Notice. When the USPTO processes the reply to the Notice, the USPTO will generate another Filing Receipt incorporating the requested corrections (if appropriate).

Applicant(s)

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Domestic Priority data as claimed by applicant

This application is a 371 of PCT/JP98/04881 10/28/1998

Foreign Applications

If Required, Foreign Filing License Granted: 04/10/2003

Projected Publication Date: None, application is not eligible for pre-grant publication

Non-Publication Request: Yes

Early Publication Request: No

APR 21
 3 46 PM '03
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Title

Polishing apparatus and a semiconductor manufacturing method using the same

Method for producing semiconductors using the apparatus

Preliminary Class

451

**LICENSE FOR FOREIGN FILING UNDER
Title 35, United States Code, Section 184
Title 37, Code of Federal Regulations, 5.11 & 5.15**

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